

Modeling and computational studies of surface shape dynamics of ultrathin single-crystal films with anisotropic surface energy, part I

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Substrate growth of high-quality thin solid films and crystals is extremely challenging due to very tough environments: temperatures higher than 1000 C, local stresses in the MPa range

30 years of crystal growth research:

- Growth mechanisms still are not well understood →
- Long delay in the transition of imagined applications from the growth experiment stage to a nanoscale semiconductor device-building stage

Example: Formation of single-crystal, nanometer-sized “islands” from the initially continuous single-crystal film grown on a single-crystal substrate made from different material than the film
(*Stranski-Krastanow heteroepitaxial thin film growth*)

Motivations, continued: Thin Film Crystal Growth

Flat film



Figure : Flat, single-crystal semiconductor film ($Si_{1-x}Ge_x$ on Si) grown by MBE or CVD to height h_0 .

and then, suddenly, ... **Instability and pattern formation**

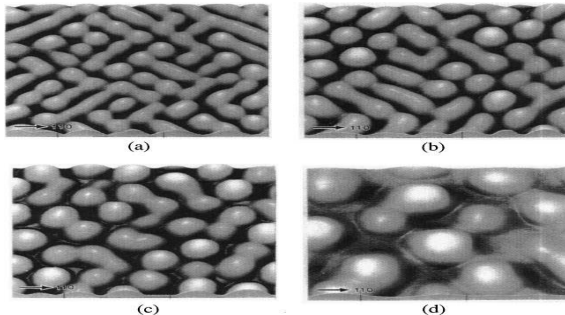


Figure : AFM images of 10nm-thick $Si_{0.82}Ge_{0.18}/Si$ alloy films annealed at 850 C for (a) 1 min, (b) 5 min, (c) 20 min, and (d) 2 h (from [1]).

Motivations, continued: Thin Film Crystal Growth

The ultimate goal: production of uniform, defect-free superlattices of nicely-shaped crystal islands (pyramids, domes, cubes, etc.)

- Methods of shape and order control must be perfected
- Factors influencing **pattern formation and pattern coarsening** must be fully understood

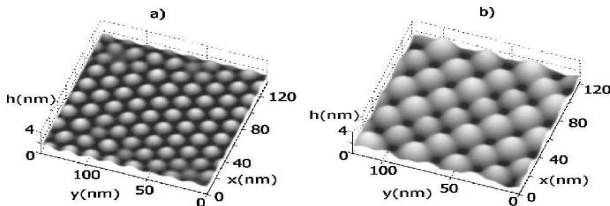


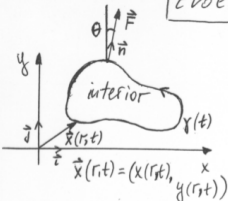
Figure : Computer simulation results of a mathematical model (from [2]).
(a) Stationary hexagonal lattice; (b) Stationary square lattice. **This is MUCH better than the best experiments to-date !**

Motivations, continued: Mathematics

High-order, very nonlinear "geometric" evolution PDEs comprise the models of thin solid films → complicated mathematics

What is a geometric PDE?

Equations of Motion for Evolving Curves


$$\vec{n}(r,t) \cdot \frac{\partial \vec{x}(r,t)}{\partial t} = F(k(r,t), k_r(r,t), \dots)$$
$$\vec{x}(r,0) = \gamma(0) \text{ prescribed}$$
$$r \in [0, R] : \text{parameter (not arc length)}$$
$$\vec{n}(r,t) = \vec{i} \frac{g}{y_r} - \vec{j} \frac{g}{x_r}, \text{ where}$$
$$g = (x_r^2 + y_r^2)^{1/2} : \text{metric (structure) function.}$$

g measures stretch of parametrisation, since $ds = g(r,t) dr$, where s is arc length

Also, $\vec{x}(0,t) = \vec{x}(R,t) : \text{b.c.}$

$$K(r,t) = \frac{1}{g^3} (y_{rr} x_r - x_{rr} y_r)$$

Modeling approaches

- Continuum: this talk. Provides qualitative information on the process
- Atomistic (Molecular Dynamics, Kinetic Monte-Carlo): computationally expensive, thus limited to a few thousand atoms and short time scales (microseconds)
- Atomistic/continuum multiscale methods: state-of-the art, combine best of both worlds

The simplest continuum approach: PDE IBVP for the **film height function** $h = h(x, y, t)$, $0 \leq x \leq X$, $0 \leq y \leq Y$:

$$h_t = F(h, h_x, h_y, h_{xx}, h_{yy}, \dots)$$

+ the initial condition: $h(x, y, 0) = h_0(x, y)$

+ the boundary conditions:

$h(0, y, t)$, $h(X, y, t)$, $h(x, 0, t)$, $h(x, Y, t)$ are prescribed

This approach works iff the films surface does not overhang onto itself (is a graph); otherwise, a parametric formulation (the previous slide)

Physical factors: Epitaxial Stress

1. Compressive or tensile stress generated by lattice mismatch of the film and the substrate

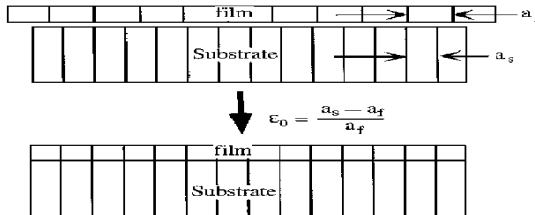


Figure : A heteroepitaxial thin-film structure. The mismatch between the lattice parameters of the film and substrate is accommodated by a (compressive) elastic stress in the film (from [1]).

Physical factors, continued: Surface diffusion I

2. Diffusive mass transport of **adatoms** along the film surface.

- Is very fast due to the high-T environment
- Causes the *morphology* (= shape) of the film surface to evolve continuously

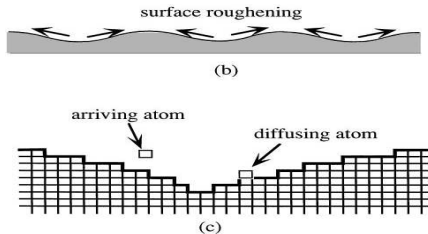


Figure : Continuum and atomistic view of surface diffusion (from [1]).

Introduce the **surface chemical potential**

$\mathcal{M}(h, h_x, h_y, \dots) = \mathcal{M}_\gamma + \mathcal{M}_e + \mathcal{M}_w + \dots$, where

γ : surface energy density;

e : elastic energy density; w : wetting energy density

Gradients of \mathcal{M} drive the diffusion flux of adatoms along the surface: $j = -\nabla \mathcal{M}(h, h_x, h_y, \dots)$ (thermodynamic Fick's law)

Thus surface height $h(x, y)$ changes

When either $\mathcal{M}_e \neq 0$, or $\mathcal{M}_w \neq 0$, or $\mathcal{M}_e = \mathcal{M}_w = 0$, but the surface energy γ is anisotropic, the planar film is the **unstable equilibrium**, because:

In equilibrium the surface diffusion flux vanishes,

$$j = -\nabla \mathcal{M}(h, h_x, h_y, \dots) = 0 \rightarrow \mathcal{M}(h, h_x, h_y, \dots) = \text{const.},$$

where value of *const.* depends on film volume and boundary conditions.

Solution of this elliptic PDE gives equilibrium surface shape $h(x, y)$, termed the **Wulff shape**

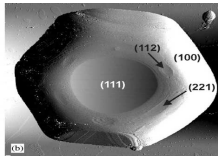


Figure : Wulff shape of a free-standing, micrometer-sized Pb crystal (from [3]).

Physical factors, continued: Surface diffusion IV

Planar film surface is the stable equilibrium only when $\mathcal{M}_e = \mathcal{M}_w = 0$, and the surface energy γ is isotropic \rightarrow the PDE $\mathcal{M}(h, h_x, h_y, \dots) = \text{const.}$ has the single linearly stable solution $h = h_0 = \text{const.}$ (will be shown later)

\mathcal{M}_γ and \mathcal{M}_w are easy to model since they are **local** quantities (defined on the film surface)

\mathcal{M}_e is very difficult to model since it is **non-local**:

- Solve the elasticity problem for deformations and stresses in the bulk of the film
- Take the solution on the film surface $h(x, y, t)$ (which is itself the problem unknown)
- \rightarrow a free-boundary problem

Physical factors, continued: Anisotropy of surface energy density I

The film surface is the geometrical boundary of the crystalline solid
→

- Inherits the short- and long-range order of the arrangement of atoms in the crystal lattice →
- A surface is a collection of finite-size atomic planes, called **facets**. Each facet has distinct surface energy γ , which is different from the surface energy of another facet with different *orientation* →
- 3. $\gamma = \gamma(\theta(x, y), \phi(x, y))$, where θ and ϕ are two angles of the *unit normal* to the surface at point (x, y)

Physical factors, continued: Anisotropy of surface energy density II

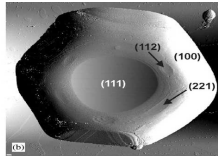


Figure : Wulff shape of a free-standing, micrometer-sized Pb crystal grown from a seed (from [3]).

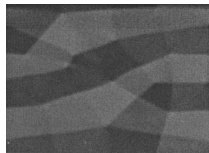
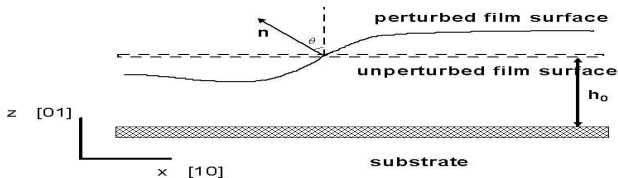


Figure : Facetted surface of a film. Facets appear as regions of uniform color (from [4]).

Physical factors, continued: Anisotropy of surface energy density III



Dimensionless anisotropic surface energy for typical 1D surfaces:

$$\gamma^{(f)}(\theta) = 1 + A \cos 4\theta, \quad A \text{ is the anisotropy strength}$$

For $A > 1/15$ (strong anisotropy) there exist solutions of $\gamma^{(f)} + \gamma_{\theta\theta}^{(f)} < 0$:

- At such θ there is a corner (formed by two facets) on the equilibrium Wulff shape (Wulff'1901, Herring'1950s)

It is said that these orientations are *missing* from the equilibrium shape

Physical factors, continued: Anisotropy of surface energy density IV

$\tilde{\beta} = \gamma^{(f)} + \gamma_{\theta\theta}^{(f)}$: the **surface stiffness**

Evolution PDEs are *ill-posed* when the Wulff shape of a crystal has corners (when $\tilde{\beta} < 0$)

Ill-posedness means (some) solutions are exponentially growing.

Example: the backward heat equation $h_t = -h_{xx} \rightarrow$

$$h(x, t) = \exp(k^2 t) \cos kx$$

Question: how to compute surface dynamics with corners ?

Answer: need to *regularize* (penalize corners) ... will discuss later

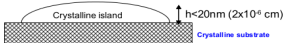
4. Energy of a long-range molecular repulsion or attraction between the atoms of the film surface and the atoms of the substrate surface

Long-range \equiv larger than atomic length: 0.1 - 10 nm

For some film-substrate materials an interaction is repulsive \rightarrow film always covers the substrate everywhere: substrate can't get exposed. *The film **wets** the substrate.* Example: SiGe alloy on Si

For other film-substrate materials an interaction is attractive \rightarrow film tries to expose substrate. *The film **does not wet** the substrate.* Example: Si on *amorphous* SiO₂ (silicon-on-insulator)

Physical factors, continued: Wetting energy II



“Wetting” island (solid 1 on substrate 1):
likes the substrate, tries to spread and maximize the contact area



“Non-wetting” island (solid 1 on substrate 2):
hates the substrate, tries to contract and minimize the contact area

Dewetting = dynamical transition from “wetting” to “non-wetting”

To account for W , let the surface energy be a function of film thickness: $\gamma = \gamma(\theta(x, y), \phi(x, y), h(x, y))$.

1D crystal surface: the **two-layer interpolation model** (1990s):

$$\gamma(h, \theta) = \gamma^{(f)}(\theta) + \left(G - \gamma^{(f)}(\theta) \right) e^{-h}, \quad G \text{ is the energy of the substrate}$$

$$\gamma^{(f)}(\theta) = 1 + A \cos 4\theta, \quad \lim_{h \rightarrow \infty} \gamma(h, \theta) = \gamma^{(f)}(\theta), \quad \lim_{h \rightarrow 0} \gamma(h, \theta) = G$$

Now:

$$\mathcal{M}_w = \frac{\partial \gamma(h, \theta)}{\partial h} \cos \theta = \left(\gamma^{(f)}(\theta) - G \right) e^{-h} \cos \theta$$

Historical background I

Stages of concept/modeling framework development

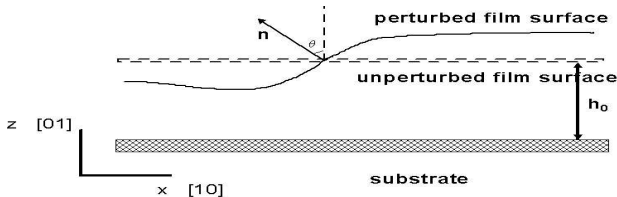
- Surface energy (including anisotropy), surface diffusion: 1950's and 1960's (William Mullins, Conyers Herring, others)
- Stress: 1970's and 1980's (Asaro, Tiller, Grinfeld, Srolovitz, others), 1990's (Spencer, Voorhees, Tersoff, Freund, others)
- Wetting energy: 2000's (Ortiz, Golovin, others)

Also, alloy composition/segregation effects have been studied since 1990s

Historical background II: Mullins-Herring problem

PDE for shape evolution by high-T surface diffusion (note: surface energy $\gamma = \text{const.}$!)*

* Derivation on request



$$z = h(x, t), \quad h_t \cos \theta = h_t (1 + h_x^2)^{-1/2} = V = -\Omega j_s, \quad \frac{\partial}{\partial s} = \cos \theta \frac{\partial}{\partial x}$$

$$j = -\frac{D\nu}{kT} \mathcal{M}_s, \quad \mathcal{M} \equiv \mathcal{M}_\gamma = \Omega \gamma \kappa, \quad \kappa = \frac{-h_{xx}}{(1 + h_x^2)^{3/2}}$$

$$\text{Thus } h_t = B \frac{\partial}{\partial x} \left((1 + h_x^2)^{-1/2} \left[\frac{-h_{xx}}{(1 + h_x^2)^{3/2}} \right]_x \right), \quad B = \frac{\Omega^2 \nu D \gamma}{kT}$$

Next, make the PDE dimensionless $\rightarrow h_0 = 1$

Linear Stability Analysis:

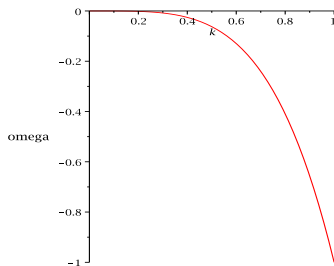
$$h = 1 + \xi(x, t) \rightarrow \xi_t = -B\xi_{xxxx}$$

Let

$$\xi(x, t) = e^{\omega t} \cos kx \equiv e^{\omega t} \operatorname{Re} \left(e^{ikx} \right)$$

Solution is shape-preserving:

$$h(x, t) = 1 + \exp(-Bk^4 t) \cos kx, \quad \omega(k) = -Bk^4$$

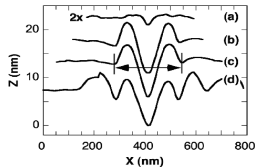
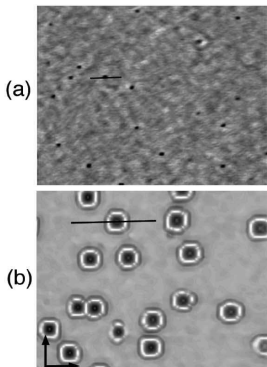


The dispersion curve $\omega(k)$

Problem: Dewetting of silicon-on-insulator (Si on *amorphous* SiO₂); strong surface energy anisotropy

AFM images at $t = 1$ h after the start of annealing at $T = 550\text{C}$.

(a) $h_0 = 5$ nm; (b) $h_0 = 20$ nm. (from [5]). **Pits form in the film !**



Problem: Dewetting of silicon-on-insulator, continued

- Lattice mismatch of Si and SiO_2 is zero \rightarrow there is no epitaxial stress in the film $\rightarrow \mathcal{M}_e = 0 \rightarrow$ no need to solve the free-boundary elasticity problem
- Alloy composition/segregation effects are not present \rightarrow
- Only two components of the chemical potential are relevant: \mathcal{M}_γ and \mathcal{M}_w

How is pitting initiated and how it proceeds ? What are the factors influencing pit width and depth ? More generally, what are the factors influencing instability of Si surface ?

Problem: Dewetting of silicon-on-insulator, continued

Nonlinear evolution PDE (dimensionless):

$$h_t = B(1 + h_x^2)^{1/2} \frac{\partial^2}{\partial s^2} (\mathcal{M}_w + \mathcal{M}_\gamma), \quad \frac{\partial}{\partial s} = (\cos \theta) \frac{\partial}{\partial x}$$

With the two-layer interpolation model for the surface energy:

$$\mathcal{M}_w = \frac{\partial \gamma(h, \theta)}{\partial h} \cos \theta = \left(\gamma^{(f)}(\theta) - G \right) e^{-h} \cos \theta,$$

$$\mathcal{M}_\gamma = (\gamma(h, \theta) + \gamma_{\theta\theta}(h, \theta)) \kappa = \tilde{\beta} \left(1 - e^{-h} \right) \kappa + G e^{-h} \kappa,$$

$$\kappa = -h_{xx} / (1 + h_x^2)^{3/2}, \quad \cos \theta = (1 + h_x^2)^{-1/2}$$

However, the PDE is ill-posed when $\tilde{\beta} \equiv \gamma^{(f)} + \gamma_{\theta\theta}^{(f)} < 0$: next slide, the cure

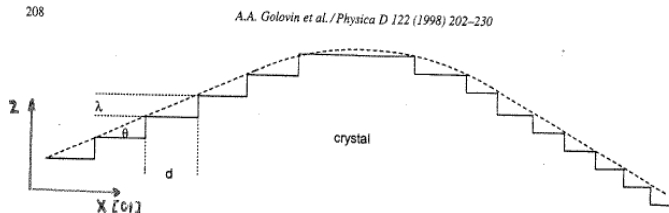
Problem: Dewetting of silicon-on-insulator, continued

To regularize the PDE we add the squared curvature dependence to $\gamma^{(f)}(\theta)$:

$$\gamma^{(f)}(\theta) = 1 + A \cos 4\theta + \frac{\Delta}{2} \kappa^2, \quad \Delta > 0 \text{ if } A > 1/15; \quad \cos 4\theta = f(\cos \theta)$$

The last term in $\gamma^{(f)}(\theta)$ is the energy penalty to form a corner, arising from repulsive interaction of micro-steps inside the corner (Golovin *et al.*'98)

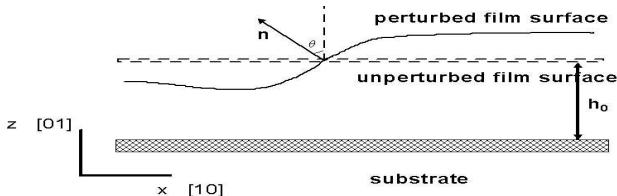
With regularization, *corners are smooth* on a small length scale and **ill-posedness is removed** ... but 6th-order derivative terms appear



Problem: Dewetting of silicon-on-insulator, continued

Plan for Linear Stability Analysis (LSA):

- (ii) Perturb the surface about the equilibrium constant height h_0 by the perturbation $\xi(x, t)$, obtain PDE for ξ
- (iii) Linearize PDE for ξ and obtain linear PDE
 $\xi_t = F(\xi, \xi_x, \xi_{xx}, \dots)$
- (iv) Take $\xi = e^{\omega t} \cos kx$ and substitute in PDE $\rightarrow \omega(h_0, k, A)$
- (v) Examine for what values of h_0, k, A the growth rate is positive or negative. $\omega < 0$: surface is stable; $\omega > 0$: surface is unstable



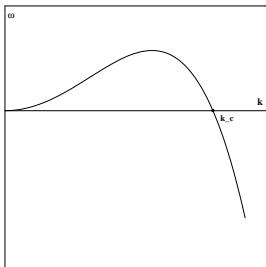
Problem: Dewetting of silicon-on-insulator, continued

The perturbation growth rate from LSA:

$$\omega(h_0, k, A) = B \left[\left(\Lambda - (G + \Lambda) e^{-h_0} \right) k^4 - (G - 1 - A) e^{-h_0} k^2 - \Delta k^6 \right]$$

$$\Lambda = 15A - 1, \Delta > 0 \quad \text{when} \quad A > 1/15 \text{ (strong anisotropy)}$$

Attractive surface-substr. interaction (non-wetting film): $0 < G < 1$



The dispersion curve $\omega(k)$; $k_c = \sqrt{\Lambda/\Delta}$: the cut-off wavenumber

Problem: Dewetting of silicon-on-insulator, continued

- If perturbation wavenumber $k > \max(k_c, k_c^{(u)})$, where

$$k_c = \sqrt{\Lambda/\Delta}, \quad k_c^{(u)} = \sqrt{-(G-1-A)/(G+\Lambda)},$$

then film of any thickness is stable

- If $k_c < k_c^{(u)}$ and $k_c < k < k_c^{(u)}$, then film is stable if $h_0 > h_0^{(c1)}$ and unstable otherwise, where

$$h_0^{(c1)} = -\ln \frac{\Lambda k^2 - \Delta k^4}{G - 1 - A + (G + \Lambda)k^2}, \quad \text{typically } 2 - 4 \text{ nm}$$

- If $k_c > k_c^{(u)}$ and $k_c^{(u)} < k < k_c$, then the film is stable if $h_0 < h_0^{(c1)}$ and unstable otherwise → **typically seen in experiments**
- If $k < \min(k_c, k_c^{(u)})$, then the film of any thickness is unstable

Problem: Dewetting of silicon-on-insulator, continued

Computer simulations of a pit using the nonlinear evolution PDE

$$h_t = F(h, h_x, h_{xx}, \dots)$$

The initial condition:

$$h(x, 0) = 1 - d \exp \left[- \left(\frac{x - 5}{w} \right)^2 \right], \quad 0 \leq x \leq 10$$

$d = 0.5$ (shallow pit) AND one of the following:

$w = 0.15$ (narrow pit), or

$w = 1$ (intermediate pit), or

$w = 2$ (wide pit)

Periodic b.c.'s at $x = 0$ and $x = 10$

$$G = 0.5, \quad A = 1/12, \quad B = 3.57 \times 10^{-3}$$

Numerical method: Non-graph (overhanging) surface shapes are possible at large deviations from (planar) equilibrium → PDE in parametric form

Let (x, z) be the components of the position vector of a point (a marker particle) on the evolving surface:

$$x_t = V \frac{z_u}{g} \quad (1)$$

$$z_t = -V \frac{x_u}{g}, \quad 0 \leq u \leq U : \text{the parameter} \quad (2)$$

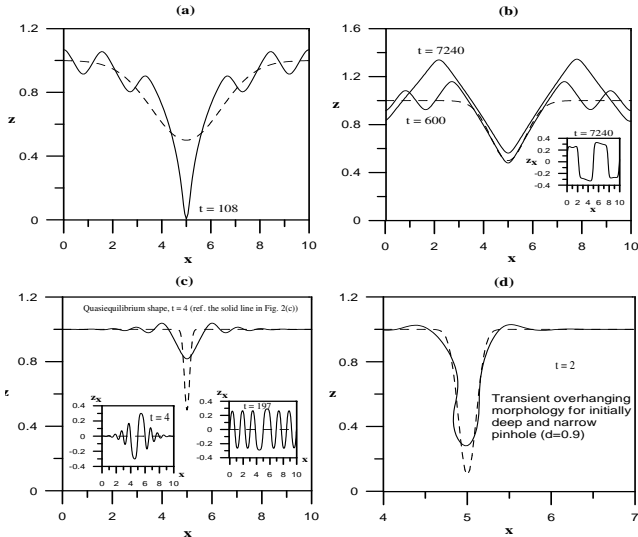
$$V = B \frac{\partial^2}{\partial s^2} (\mathcal{M}_w + \mathcal{M}_\gamma), \quad g = \sqrt{x_u^2 + z_u^2}, \quad \frac{\partial}{\partial s} = \frac{1}{g} \frac{\partial}{\partial u}$$

Use Method of Lines:

- Discretize PDE in u using FDs, leave time continuous → system of coupled ODEs in time
- Integrate using the stiff ODE solver (IRK-RADAU by Hairer & Wanner)
- To maintain accuracy, must remesh the surface grid to keep marker particles optimally spaced (ideally, equidistant in the arclength)

Problem: Dewetting of silicon-on-insulator, continued

Computer simulation results: Pit shapes



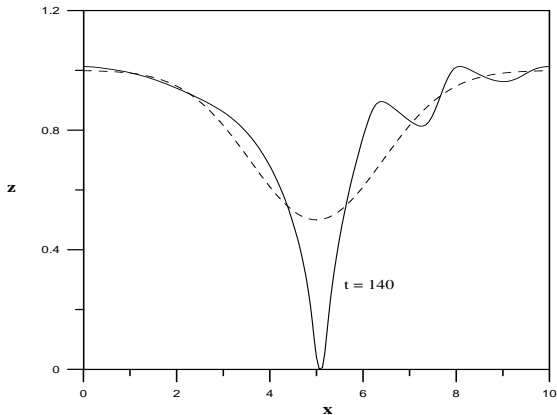
(a): $w = 2$, (b): $w = 1$, (c): $w = 0.15$

Problem: Dewetting of silicon-on-insulator, continued

Computer simulation results: Pit shapes

Rotate sample, expose different crystallographic orientation:

$$\gamma^{(f)}(\theta) = 1 + A \cos 4(\theta + \beta)$$



$$w = 2, \beta = 10^\circ$$

Other models of wetting interactions have been proposed, for instance:

Two-layer algebraic model

$$\gamma(h, \theta) = \frac{1}{2} \left(\gamma^{(f)}(\theta) + \gamma_S \right) + \frac{1}{2} \left(\gamma^{(f)}(\theta) - \gamma_S \right) f(h/\ell)$$
$$\lim_{h \rightarrow \infty} f(h/\ell) = 1, \quad \lim_{h \rightarrow -\infty} f(h/\ell) = -1$$

Let

$$f(h/\ell) = \frac{2}{\pi} \arctan \left[\left(\frac{h}{\ell} \right)^m \right], \quad m = 1, 3, 5, \dots$$

Note that

$$f(h/\ell) = 1 - \frac{2}{\pi} (h/\ell)^{-m} + \dots \quad \text{as } h \rightarrow \infty.$$

i.e., this tends to the limiting value +1 as an algebraic power. Then,

$$\mathcal{M}_w \sim 1/h^{m+1}, \quad \text{for } h \gg 1$$

- Increased stability of the equilibrium $h = 1$
- only wide and deep pinholes dewet for the same set of parameters, and only for $m = 1$

- ① H. Gao and W.D. Nix, "SURFACE ROUGHENING OF HETEROEPITAXIAL THIN FILMS", Annu. Rev. Mater. Sci. 1999, 29:173-209
- ② A.A. Golovin *et al.*, "Faceting instability in the presence of wetting interactions: A mechanism for the formation of quantum dots", PHYSICAL REVIEW B 70, 235342 (2004); B.J. Spencer *et al.*, "Morphological instability in epitaxially strained dislocation-free solid films: Linear stability theory", J. Appl. Phys. 73, 4955 (1993)
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- ④ M. Rost, "Continuum models for surface growth", preprint
- ⑤ J.L. Gray *et al.*, "Kinetic size selection mechanisms in heteroepitaxial quantum dot molecules", Phys. Rev. Lett. 92, 135504 (2004)

- ① M. Khenner, “Dewetting of an ultrathin solid film on a lattice-matched or amorphous substrate”, Physical Review B 77, (2008) 165414.
- ② M. Khenner, “Morphologies and kinetics of a dewetting ultrathin solid film”, Physical Review B 77, (2008) 245445.
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